



Initial Review
BOX AF

RESPONSE UNDER 37 CFR 1.116 - EXPEDITED
PROCEDURE - EXAMINING GROUP 1112

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GROUP 1100

#9/B
(N.E.)
#14/D

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of:

Takeshi FUKUNAGA et al.

Serial No. 08/519,420 -

Filed: August 25, 1995 -

For: A METHOD OF MANUFACTUR-

ING A SEMICONDUCTOR DEVICE

INCLUDING LASER IRRADIATION

FOLLOWED BY THERMAL

ANNEALING

) Examiner M. Padgett

) Art Unit 1112

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) Docket No. 0756-1398

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, BOX AF, Washington, D.C. 20231, on December 3, 1996.

Deborah J. Tomme
Deborah T. Tomme

AMENDMENT AFTER FINAL REJECTION

Honorable Assistant Commissioner for Patents

BOX AF

Washington, D.C. 20231

Sir:

In response to the final rejection Office Action mailed September 3, 1996, please amend the above identified application as follows.

Do NOT enter Mr. Padgett - 12/14/96